

IN THE CLAIMS:

Please amend the claims as follows.

1. (Currently Amended) An apparatus for remotely monitoring and developing steps in a semiconductor manufacturing process comprising:  
at least one remote workstation connected via a remote access link to a local workstation; and  
a test system connected via a link to the local workstation, wherein the test system comprises ancillary equipment pre-selected and operatively controlled by a client to test various functions of a device.
2. (Original) The apparatus of claim 1, further comprising a client switch that connects a client network to the at least one remote workstation.
3. (Original) The apparatus of claim 1, further comprising a host switch that connects a host network to the test system and when engaged, prevents client access to the test system.
4. (Original) The apparatus of claim 3, wherein the host switch comprises a manual switch.
5. (Original) The apparatus of claim 3, wherein the host switch comprises an ethernet switch.
6. (Original) The apparatus of claim 3, wherein the host switch comprises a computer security software.
7. (Original) The apparatus of claim 1, wherein the remote access link comprises:

- a wide area network communication line operatively coupling the local workstation to the remote workstation.
8. (Original) The apparatus of claim 7, wherein the remote access link further comprises at least one router.
9. (Original) The apparatus of claim 1, wherein the link comprises a Local Area Network including the local workstation and the test system.
10. (Cancelled)
11. (Currently Amended) The apparatus of claim 10 1, wherein the ancillary equipment further comprises a temperature forcing unit.
12. (Currently Amended) The apparatus of claim 10 1, wherein the ancillary equipment further comprises a wafer prober.
13. (Currently Amended) The apparatus of claim 10 1, wherein the ancillary equipment further comprises a device handler.
14. (Currently Amended) An apparatus for remotely monitoring and developing steps in a semiconductor manufacturing process comprising:  
a plurality of remote workstations each connected via a remote access link to a local workstation; and  
a test system connected via a link to the local workstation,  
wherein the test system comprises ancillary equipment pre-selected and operatively controlled by a client to test various functions of a device.
15. (Original) The apparatus of claim 14, wherein the local workstation includes a plurality of firewalls adapted to prevent access from one of the remote workstations to any other one of the remote workstations.

16. (Original) The apparatus of claim 14, wherein at least one of the remote access links comprises an internet connection.
17. (Original) The apparatus of claim 14, wherein at least one of the remote access links comprises a dedicated WAN technology.
18. (Original) The apparatus of claim 14, further comprising a host switch adapted to selectively connect a host networking service to the test system.
19. (Cancelled)
20. (Currently Amended) The apparatus of claim ~~19~~ 14, wherein the ancillary equipment further comprises a temperature forcing unit.
21. (Currently Amended) The apparatus of claim ~~19~~ 14, wherein the ancillary equipment further comprises a wafer prober.
22. (Currently Amended) The apparatus of claim ~~19~~ 14, wherein the ancillary equipment further comprises a device handler.
23. (Currently Amended) A method for remotely monitoring and developing steps in semiconductor manufacturing comprising:
  - running a semiconductor test system remotely from a remote workstation coupled over a link to a local workstation, the local workstation being operatively coupled to the test system;
  - monitoring the semiconductor test system remotely from the remote workstation; and
  - receiving data from the semiconductor test system at the remote workstation,

wherein monitoring the semiconductor test system comprises using at least one piece of ancillary equipment.

24. (Original) The method of claim 23, wherein the semiconductor test system comprises a semiconductor probe system for integrated circuit design debug and repair.
25. (Original) The method of claim 23, wherein the semiconductor test system comprises a test system adapted to monitor the functionality of semiconductors produced by a fabrication plant.
26. (Currently Amended) An apparatus for remotely monitoring and developing steps in a semiconductor manufacturing process comprising:
  - at least one remote workstation operatively connected via a Wide Area Network communication line to a local workstation;
  - a test system connected via a Local Area Network to the local workstation; and
  - a host network detachably connected by a host switch and a link to the test system,

wherein the test system comprises ancillary equipment pre-selected and operatively controlled by a client to test various function of a device.
27. (Original) The apparatus of claim 26, further comprising a video camera networked to the test system.
28. (New) The method of claim 23, further comprising:
  - controlling the semiconductor test system remotely from the remote workstation.
29. (New) The apparatus of claim 1, further comprising:
  - a video camera networked to the test system.